

# CPSHR2 – CRYO POSITIONING STAGE HIGH RESONANCE 2



## **Features**

- xyz motion for very stable cavity measurements
- Parallel kinematics for optimized stiffness
- High resonance frequencies
- Coarse motion using Cryo Linear Actuators
- Position feedback option -COE
- Scanning motion integrated
- 20mK to 375K, vacuum compatible
- Compatible with CVIP2 vibration isolator

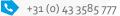
#### **Description / Applications**

The Cryo Positioning Stage High Resonance (CPSHR) is a XYZ positioning stage developed for operation in a cryo-vacuum environment, especially suited for very stable cavity measurements. Parallel kinematics result in a light and stiff stage with very high internal resonance frequencies, making it less sensitive to floor vibrations. The CPSHR2 has a large stroke and the phosphor bronze construction offers the optimal combination of thermal conductance and high resonances at mK temperatures.

Specifications General info		
Type of motion		
/1	xyz with parasitic angular motion	
Parasitic angle from xy stroke	14 mrad/mm, about the x and y axis	
1st natural frequency	xy: 1,2 kHz / z: 2,2 kHz (xy: 0,55 kHz for the -S models)	
Dimensions	See drawings below	
Operational environmental conditions	20 mK to 375 K, ambient to UHV	
Weight	1230 g, -COE adds 30 g	
Stepping motion		
Travel range	x ±10,1 mm / y ±11,6 mm / z ±3,0 mm (not simultaneously)	
Actuator	CLA2601, see drawings for calculating actuator outputs to system motion	
Minimal step size @ 300 K	5 nm	
Minimal step size @ 4 K	1 nm	
Scanning motion		
Actuator	Piezo actuators, see drawings for calculating piezo outputs to system motion	
Scanning range @ 300 K, typical	x 46 μm / y 53 μm / z 8 μm (not simultaneously)	
Scanning range @ 4 K, typical	x ±18,4 μm / y ±21.3 μm / z ±1,6 μm (not simultaneously)	
Minimal step size	Sub-nm	
Drive voltage @ 300 K	-30 V to 120 V	
Drive voltage @ 4 K	-150 V to 150 V	
Forces and load capacity		
Load capacity	200 g	
Materials		
Main body	Phosphor bronze	
CLA2601	Stainless steel, ceramic, piezo actuator*	
Scanner	Piezo actuator*	
*Piezo actuator	Low voltage multilayer, ceramic insulated	
Model specific information		
-S	xyz scanner added, see above for range	
-COE	Optical Encoder on each CLA2601, 850 pulses per revolution, equivalent to 294 nm axial	
	displacement	
Electronics CPSC		
Controller Base Cabinet	САВ	
Driver for stepping and scanning	CADM or PSM (scanning only)	
Position readout	OEM	

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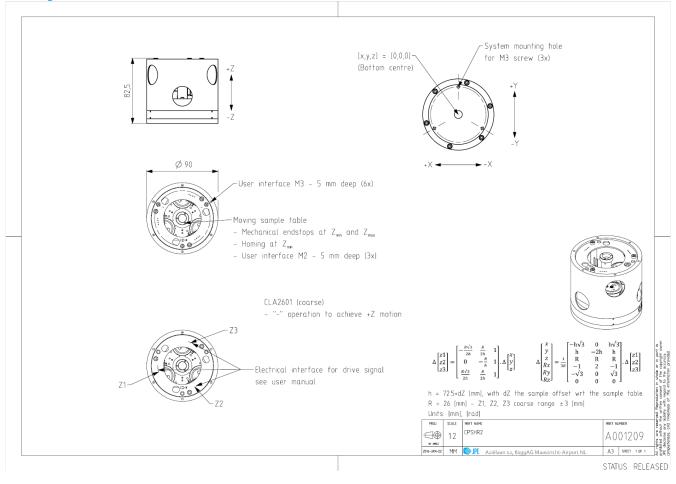




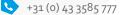
## **Ordering Information**

Available models CPSHR2 CPSHR2-S	Cryo Positioning Stage High Reson Cryo Positioning Stage High Reson	
CPSHR2-COE	Cryo Positioning Stage High Resonance 2-Cryo Optical Encoder	
CPSHR2-S-COE	Cryo Positioning Stage High Resonance 2-Scanner-Cryo Optical Encoder	
Available Options		
-HV	Upgrade to High Vacuum compatibility	
-UHV	Upgrade to Ultra High Vacuum compatibility	
Accessories		
AKM1	Accessory Kit Mechanical 1	
AKE1	Accessory Kit Electrical 1	
Mechanical and electrical information		Contact
Download 3D step files and manuals from: https://www.jpe-innovations.com/cryo-nano-products/		For quotations, specials, or engineering services, please contact us at: https://www.jpe-innovations.com/contact/

### Drawings

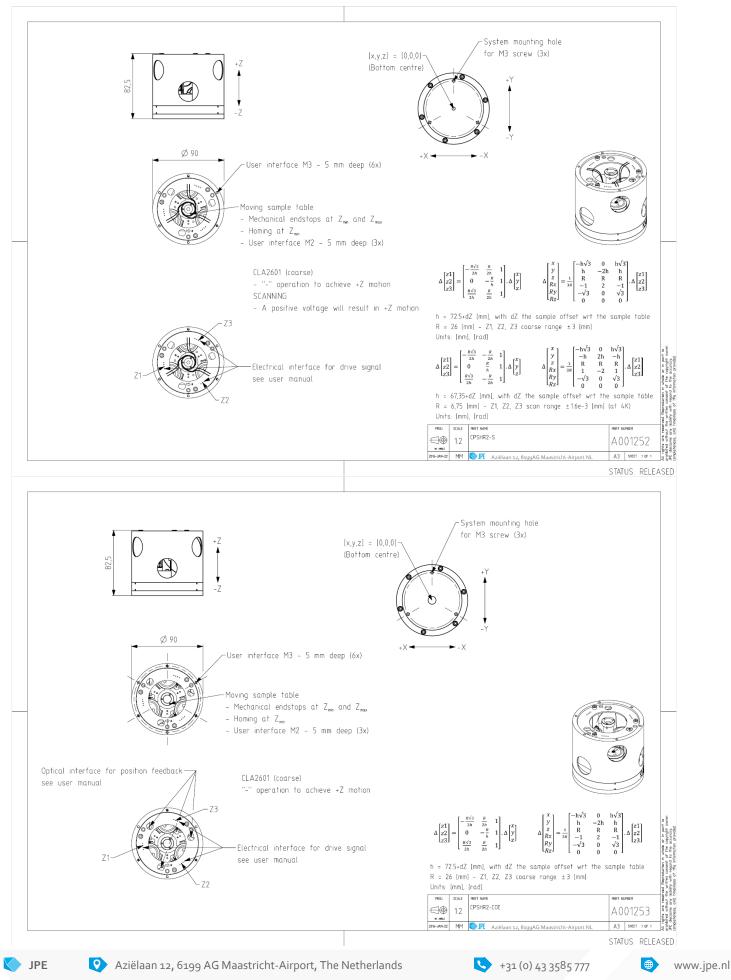






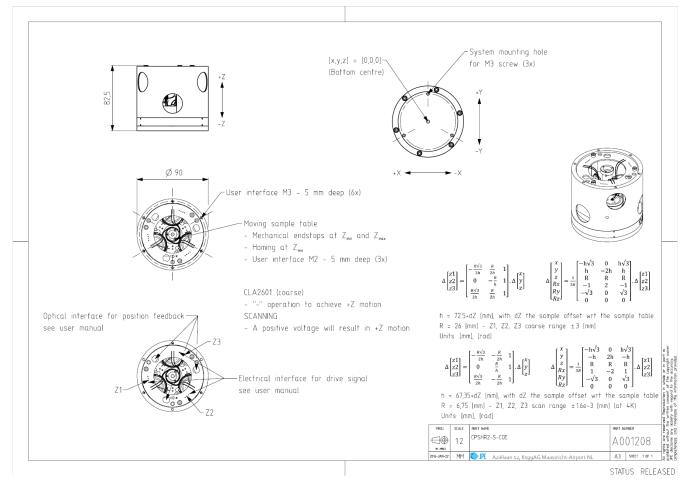






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